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Contents

vii Conference Committee

SESSION 1	OFF-AXIS AND FREEFORM OPTICS
12778 02	Advances in freeform manufacturing [12778-2]
12778 03	Ultrasonic machining of optical and ceramic materials [12778-5]
12778 04	Curvature polishing for light-weight, thin reflective optics [12778-6]
SESSION 2	MATERIALS CONSIDERATIONS FOR HIGH-VOLUME/HIGH-PRECISION OPTICS
12778 05	Rotative printing processes for polymer waveguide manufacturing [12778-7]
12778 06	Integrated optical fluid sensor in glass [12778-8]
12778 07	Thermal consideration examples for precision diamond turning [12778-10]
12778 08	Effect of rake angle for diamond turning of tungsten carbide [12778-11]
SESSION 3	MANUFACTURING CONSIDERATIONS FOR HIGH-VOLUME/HIGH-PRECISION OPTICS
12778 09	Decenter measurement of singlets and assembled optics containing cylindrical surfaces [12778-12]
12778 0A	Year one into ELT M1 segments manufacturing [12778-13]
12778 OB	The Satisloh plasma polisher: plasma surface figuring ultra precision optics [12778-14]
12778 OC	Centration error of an aspheric surface based on different datum construct [12778-15]
SESSION 4	FINISHING METHODS
12778 0D	Process optimization for high removal rates with MRF [12778-17]

iii

12778 OE Advancements in cerium oxide slurry development for precision optics [12778-18]

12778 OF Effect of polishing times for glass optics after laser-assisted single point diamond turning [12778-19]

SESSION 5 METHODS FOR NON-ROTATIONALLY SYMMETRIC OPTICS

- Measurement of surface form of cylindrical optics using non-contact multiwavelength interferometry [12778-23]
 A multi-sensor optical coordinate measurement machine for measuring freeform optical
- surface form and reference fiducial position [12778-24]
- 12778 0J Efficient testing and analysis of off axis parabolas with high off axis angles [12778-26]
- 12778 0K Benchmarking Shack-Hartmann measurements of spatial light modulator output for the reconfigurable null of rectangular freeform optics [12778-27]

SESSION 6 WAVEFRONT METROLOGY METHODS

- 12778 OL Wavefront testing of optical windows and mirrors [12778-28]
- 12778 0M Low coherence interferometry for mid-IR precision optics manufacturing [12778-31]
- 12778 ON Measurement of radius of curvature with a low-coherence flatness interferometer [12778-32]

SESSION 7 ILLUMINATION-DRIVEN METROLOGY

- 12778 00 Dynamic illumination in phase-shifting interferometry [12778-34]
- 12778 OP Transmission sphere calibration using a Fresnel zone CGH [12778-35]
- 12778 0Q Absolute shape measurement with coaxial deflectometry: towards interferometric accuracy [12778-36]

SESSION 8 AUTOMATED OPTICAL MANUFACTURING AND METROLOGY

- 12778 OR Automation in optical manufacturing: beveling and part handling [12778-37]
- 12778 0S Multi-target regression and cross-validation for non-isothermal glass molding experiments with small sample sizes [12778-38]

SESSION 9 MATERIALS AND THIN FILMS I

12778 0U Advancements in thin-film coating metrology [12778-43]

12778 0V Low and ultralow RI materials [12778-46]

SESSION 10 MATERIALS AND THIN FILMS II

12778 0X **Prism coupling refractometry: enhancing precision, accuracy, and repeatability in the infrared** [12778-50]

SESSION 11 NEW PERSPECTIVES TO CLASSICAL PROBLEMS

- 12778 0Y Repositioning and locking method for off-axis optical system using mechanical measurement [12778-53]
- 12778 0Z Updating the peak-to-valley (PV) irregularity specification for the modern world [12778-54]

SESSION 12 NOVEL APPROACHES TO OPTICAL FABRICATION AND TESTING

- 12778 10 Magnetorheological finishing performance near the edge of optical apertures as a function of edge profile [12778-55]
- 12778 11 Total process solution for the grinding and polishing of precision optics [12778-56]
- 12778 12 Subsurface damage assessment of femtosecond laser-processed surfaces [12778-57]

POSTER SESSION

- 12778 13 Diffraction efficiencies of three types of bioplastic gratings based on chitosan from seafood waste [12778-60]
- 12778 14 Analysis of low-spatial frequency response in magnetorheological finishing process [12778-62]
- 12778 15 Comparison of nanometer surface roughness on aluminum mirrors using diamond turning for accelerator [12778-63]

- 12778 16 Crystallographic effect of elastic recovery on surface roughness of ultra-precision diamond turning machined polycrystalline ZnS [12778-64]
- 12778 17 Effect of ultrasonic vibration on ultra precision diamond turning of polycrystalline zinc sulfide [12778-66]